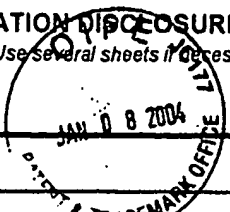


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U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
A.M.	6,440,520	08/27/02	Baglin et al.			
I	6,331,364	12/18/01	Baglin et al.			
I	6,383,597	05/07/02	Fullerton et al.			

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

A.M.		Bruenger et al., "Ion projection lithography for resistless patterning of thin magnetic films", 25th International Conference on Micro and Nano Engineering, Rome Italy, 21-23 September 1999 and Microelectron. Eng. (Netherlands), Vol. 53, No. 1-4, June 2000, Pages 605-608.
A.M.		Eugene Chen, et al., "Magnetic tunnel junction pattern technique", Silicon Magnetic Systems, Cypress Semiconductor, San Jose, CA, Journal of Applies Physics, Volume 93, Number 10, May 15, 2003, p. 8379.

EXAMINER

ANH D. MAI

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U.S. PATENT DOCUMENTS

[illegible]

FOREIGN PATENT DOCUMENTS

[illegible]

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

A.M		B.D. Terris et al., "Patterning magnetic films by ion beam irradiation", J. Appl. Phys., (USA), Vol. 87, No. 9, Pt. 1-3, May 1, 2000, pp.7004-6.
A.M		Corporate Associates, "Physics Helps Redesign Dow Chemical," 39 The Industrial Physicist, April 1999, American Institute of Physics, page 1.

EXAMINER

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